

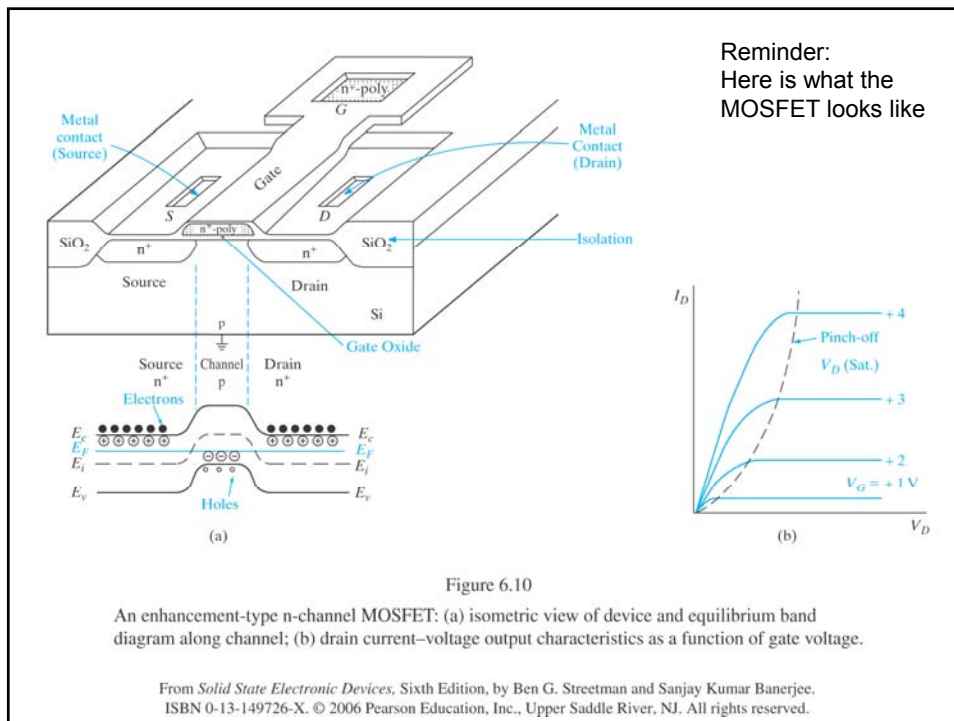
*EE415/515 Fundamentals
of Semiconductor Devices
Fall 2012*

**Lecture 11:
MOSFET
(Chapter 10.3, 10.4)**

10/29/2012

J. E. Morris

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N-channel MOSFETs: Enhancement & Depletion modes

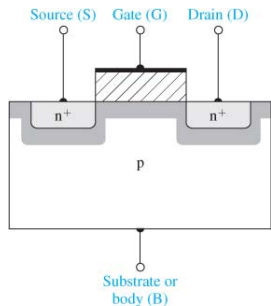


Figure 10.34 | Cross section and circuit symbol for an n-channel enhancement mode MOSFET.

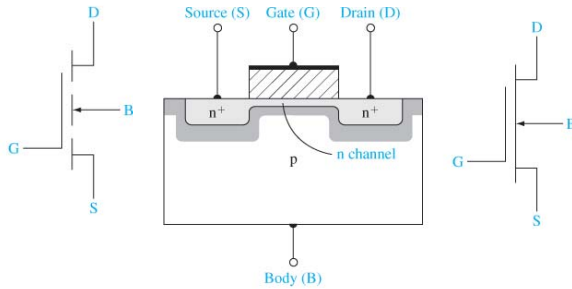


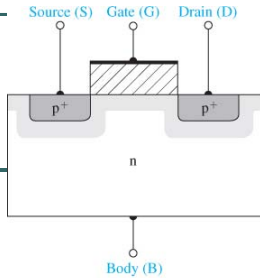
Figure 10.35 | Cross section and circuit symbol for an n-channel depletion mode MOSFET.

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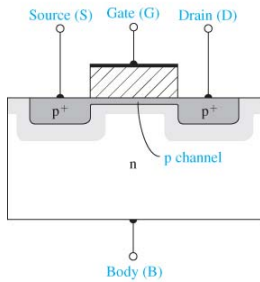
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P-channel MOSFETs: Enhancement & Depletion modes



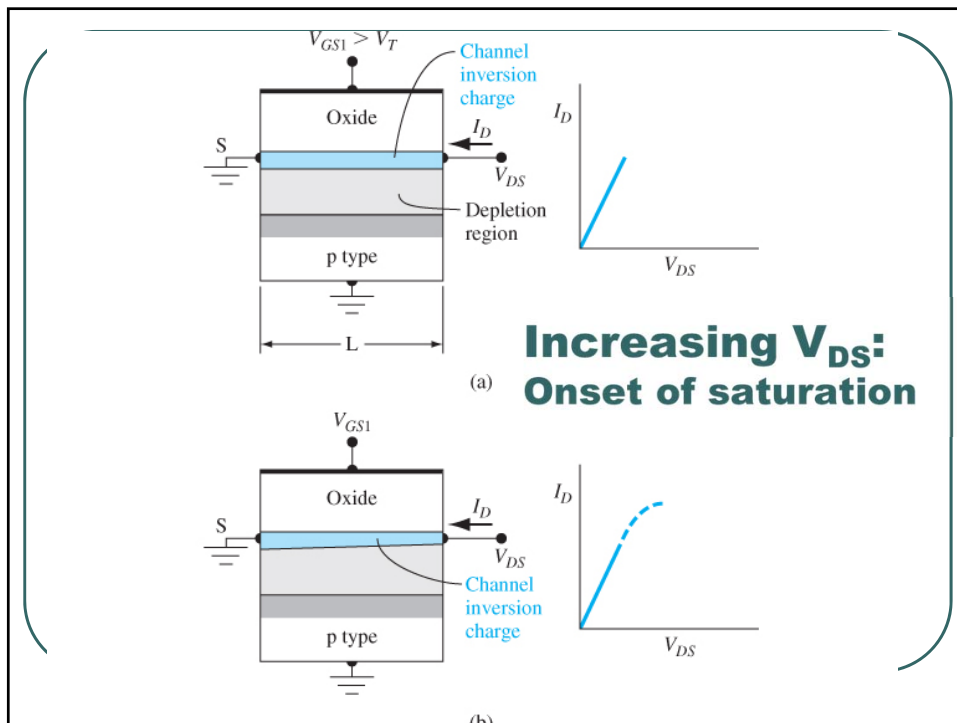
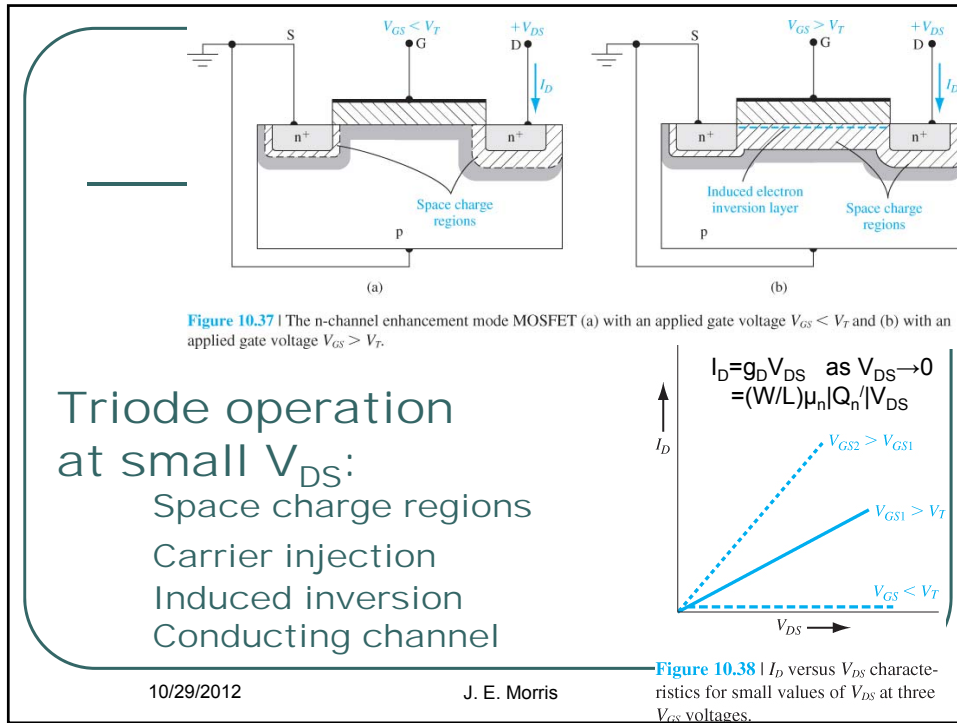
(a)

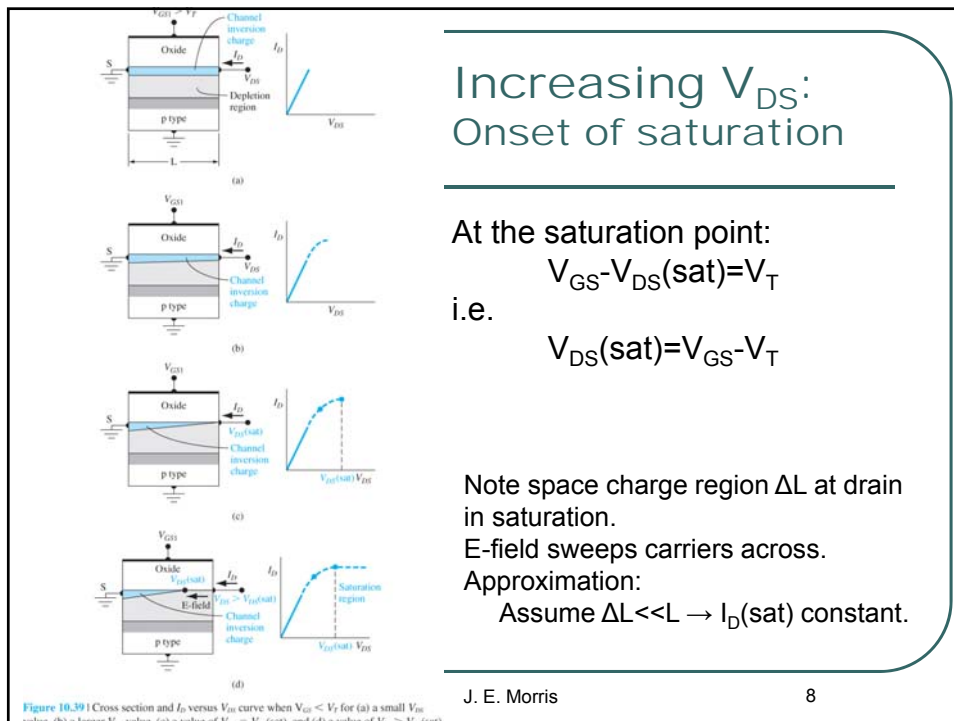
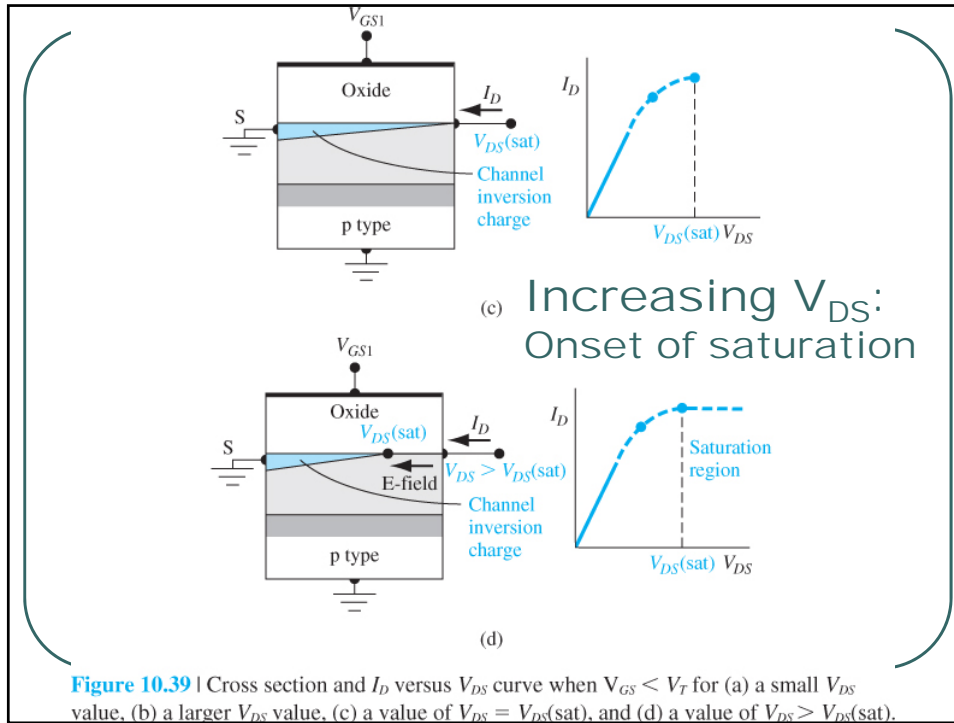


(b)

Figure 10.36 | Cross section and circuit symbol for (a) a p-channel enhancement mode MOSFET and (b) a p-channel depletion mode MOSFET.

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N-channel MOSFET characteristics: Note non-linear triode region

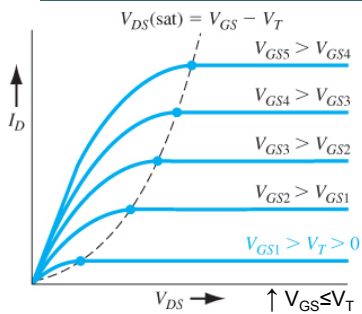


Figure 10.40 | Family of I_D versus V_{DS} curves for an n-channel enhancement mode MOSFET.

See later :

$$\begin{aligned}
 I_D &= \frac{W\mu_n C_{ox}}{2L} [2(V_{GS} - V_T)V_{DS} - V_{DS}^2] \\
 &= \frac{k'_n}{2} \frac{W}{L} [2(V_{GS} - V_T)V_{DS} - V_{DS}^2] \\
 &= K_n [2(V_{GS} - V_T)V_{DS} - V_{DS}^2]
 \end{aligned}$$

where $k'_n = \mu_n C_{ox}$ is the process conduction parameter

and $K_n = \frac{k'_n}{2} \frac{W}{L} = \frac{W\mu_n C_{ox}}{2L}$ is the conduction parameter

In saturation :

$$I_D = \frac{W\mu_n C_{ox}}{2L} (V_{GS} - V_T)^2$$

N-channel depletion mode

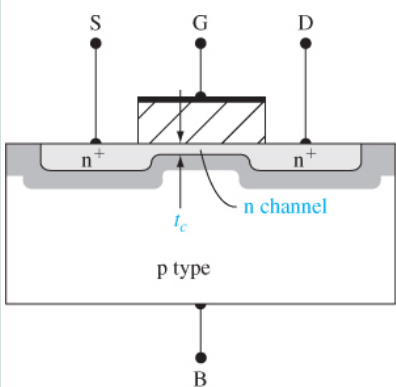


Figure 10.41 | Cross section of an n-channel depletion mode MOSFET.

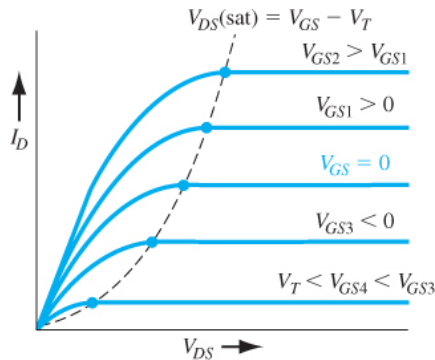
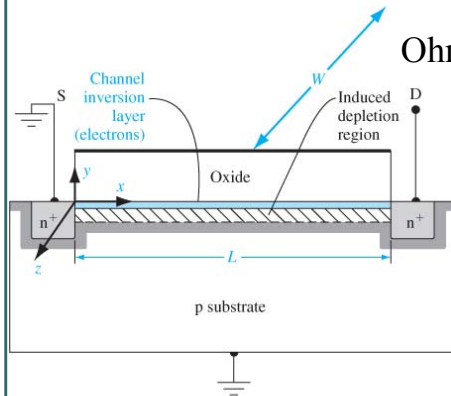


Figure 10.42 | Family of I_D versus V_{DS} curves for an n-channel depletion mode MOSFET.

I-V Characteristics



Ohm's Law :

$$J_x = \sigma E_x = en\mu_n E_x$$

$$I_x = \int_y \int_z J_x dy dz$$

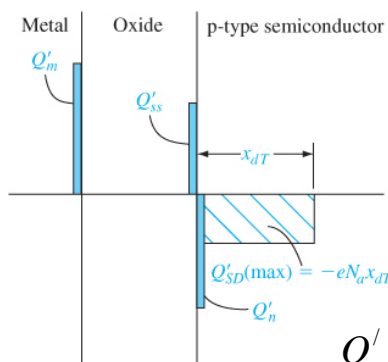
$$= W\mu_n E_x e \int_y n(y) dy$$

$$= -W\mu_n Q'_n E_x$$

$I_x, E_x \Rightarrow$ constant along channel

Figure 10.43 | Geometry of a MOSFET for I_D versus V_{DS} derivation.

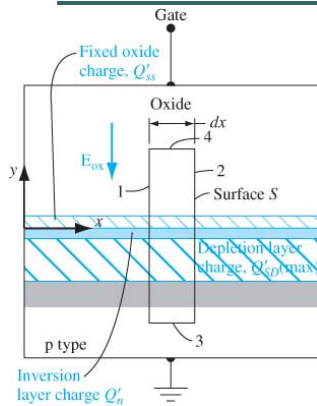
I-V Characteristics: Charge neutrality



$$Q'_m + Q'_{ss} + Q'_n + Q'_{SD}(\text{max}) = 0$$

Figure 10.44 | Charge distribution in the n-channel enhancement mode MOSFET for $V_{GS} > V_T$.

I-V Characteristics: Gauss's Law



$$\oint_s \epsilon E_n dS = -\epsilon_{ox} E_{ox} W dx$$

$$= Q_T = [Q'_{ss} + Q'_n + Q'_{SD}(\max)] W dx$$

i.e.

$$-\epsilon_{ox} E_{ox} = Q'_{ss} + Q'_n + Q'_{SD}(\max)$$

Figure 10.45 | Geometry for applying Gauss's law.

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I-V Characteristics: Oxide field V_x is channel potential (wrt S) at x

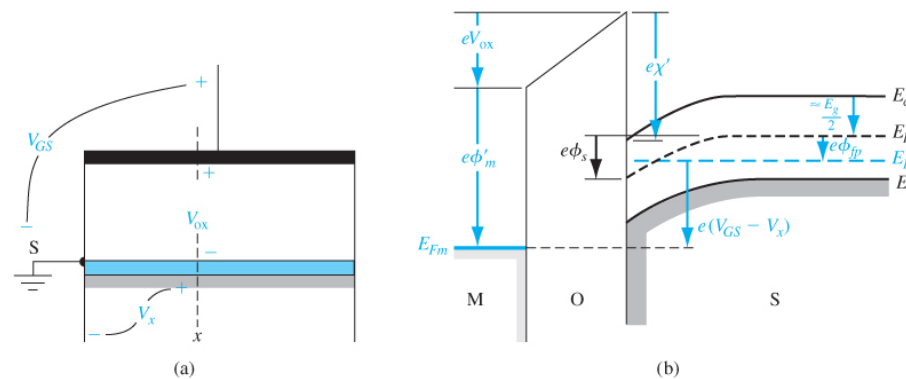


Figure 10.46 | (a) Potentials at a point x along the channel. (b) Energy-band diagram through the MOS structure at the point x .

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I-V Characteristics: Oxide field

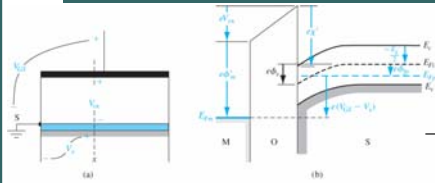


Figure 10.46 (a) Potentials at a point x along the channel. (b) Energy-band diagram through the MOS structure at the point x .

$$E_{Fp} - E_{Fn} = e(V_{GS} - V_x)$$

$$= e \left[(\phi'_m + V_{ox}) - \left(\chi' + \frac{E_g}{2e} - \phi_s + \phi_{fp} \right) \right]$$

$$V_{GS} - V_x = V_{ox} + 2\phi_{fp} + \phi_{ms}$$

using $\phi_s = 2\phi_{fp}$ for inversion

Hence:

$$-\epsilon_{ox} E_{ox} = \frac{-\epsilon_{ox}}{t_{ox}} V_{ox} = \frac{-\epsilon_{ox}}{t_{ox}} [(V_{GS} - V_x) - (\phi_{ms} + 2\phi_{fp})]$$

$$= -C_{ox} \left[(V_{GS} - V_x) - \left(V_T + \frac{Q'_{ss} + Q'_{SD}(\max)}{C_{ox}} \right) \right]$$

$$= Q'_{ss} + Q'_n + Q'_{SD}(\max)$$

So $I_x = -W\mu_n E_x Q'_n$

$$= -W\mu_n \left(-\frac{dV_x}{dx} \right) (-C_{ox} [(V_{GS} - V_x) - V_T])$$

$$= -W\mu_n C_{ox} \frac{dV_x}{dx} [(V_{GS} - V_x) - V_T]$$

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I-V Characteristics: Final equations

$$I_x = -W\mu_n C_{ox} \frac{dV_x}{dx} [(V_{GS} - V_x) - V_T]$$

$$\int_0^L I_x dx = -W\mu_n C_{ox} \int_{V_x(0)}^{V_x(L)} [(V_{GS} - V_x) - V_T] dV_x$$

$$I_D = -I_x = \frac{W\mu_n C_{ox}}{L} \left[(V_{GS} - V_T)V_{DS} - \frac{1}{2}V_{DS}^2 \right]$$

for $V_{GS} \geq V_T$ and $0 \leq V_{DS} \leq V_{DS}(sat)$
 where $V_x(0) = 0$ & $V_x(L) = V_{DS}$

$$Max I_D \Rightarrow \frac{\partial I_D}{\partial V_{DS}} = 0$$

when $V_{GS} - V_T = V_{DS} = V_{DS}(sat)$

For $V_{DS} \geq V_{DS}(sat)$, $I_D = I_D(sat)$

$$= \frac{W\mu_n C_{ox}}{L} \left[(V_{GS} - V_T)V_{DS}(sat) - \frac{1}{2}V_{DS}(sat)^2 \right]$$

$$= \frac{W\mu_n C_{ox}}{2L} (V_{GS} - V_T)^2$$

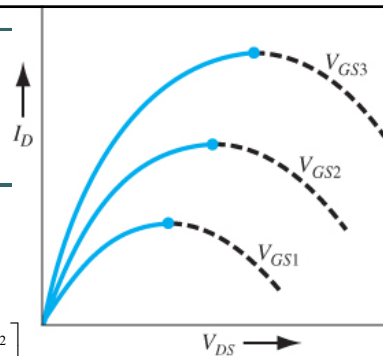


Figure 10.47 | Plots of I_D versus V_{DS} from Equation (10.62).

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Ex 10.7 N-channel Si MOSFET: $\mu_n=650\text{cm}^2/\text{V}\cdot\text{s}$, $t_{\text{ox}}=8\text{nm}$, $W/L=12$, $V_T=0.40\text{V}$. Find the drain current for (a) $V_{\text{GS}}=0.8\text{V}$, (b) $V_{\text{GS}}=1.2\text{V}$, & (c) $V_{\text{GS}}=1.6\text{V}$, if the transistor is biased in the saturation region.

$$\text{We find } C_{\text{ox}} = \frac{\epsilon_{\text{ox}}}{t_{\text{ox}}} = \frac{(3.9)(8.85 \times 10^{-14})}{80 \times 10^{-8}} = 4.314 \times 10^{-7} \text{ F/cm}^2$$

$$\text{Then } k'_n = \mu_n C_{\text{ox}} = (650)(4.314 \times 10^{-7}) = 2.804 \times 10^{-4} \text{ A/V}^2 \quad \text{or } k'_n = 0.2804 \text{ mA/V}^2$$

$$\text{Now } I_D = \frac{k'_n}{2} \cdot \frac{W}{L} (V_{\text{GS}} - V_T)^2 = \frac{0.2804}{2} (12)(V_{\text{GS}} - 0.4)^2$$

$$\text{(a) } I_D = (1.6826)(0.8 - 0.4)^2 = 0.269 \text{ mA}$$

$$\text{(b) } I_D = (1.6826)(1.2 - 0.4)^2 = 1.077 \text{ mA}$$

$$\text{(c) } I_D = (1.6826)(1.6 - 0.4)^2 = 2.423 \text{ mA}$$

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$$I_D = \frac{W\mu_n C_{\text{ox}}}{L} \left[(V_{\text{GS}} - V_T)V_{\text{DS}} - \frac{1}{2}V_{\text{DS}}^2 \right] \quad \& \quad I_D = \frac{W\mu_n C_{\text{ox}}}{2L} (V_{\text{GS}} - V_T)^2$$

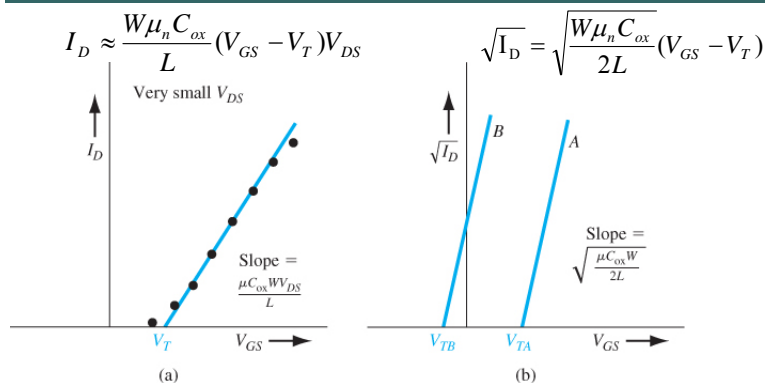


Figure 10.48 | (a) I_D versus V_{GS} (for small V_{DS}) for enhancement mode MOSFET. (b) Ideal $\sqrt{I_D}$ versus V_{GS} in saturation region for enhancement mode (curve A) and depletion mode (curve B) n-channel MOSFETs.

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Ex 10.8 N-channel Si MOSFET: $W=6\mu\text{m}$, $L=1.5\mu\text{m}$, $t_{ox}=8\text{nm}$. When the transistor is biased in the saturation region, the drain current is $I_D(\text{sat})=0.132\text{mA}$ at $V_{GS}=1.0\text{V}$ and $I_D(\text{sat})=0.295\text{mA}$ at $V_{GS}=1.25\text{V}$. Determine the electron mobility and threshold voltage.

We find $C_{ox} = \frac{\epsilon_{ox}}{t_{ox}} = \frac{(3.9)(8.85 \times 10^{-14})}{80 \times 10^{-8}} = 4.314 \times 10^{-7} \text{ F/cm}^2$

$I_D(\text{sat}) = \frac{W\mu_n C_{ox}}{2L} (V_{GS} - V_T)^2$ Then

$\sqrt{I_{D2}(\text{sat})} - \sqrt{I_{D1}(\text{sat})} = \sqrt{\frac{W\mu_n C_{ox}}{2L}} (V_{GS2} - V_{GS1})$

$\sqrt{0.295 \times 10^{-3}} - \sqrt{0.132 \times 10^{-3}} = 1.7176 \times 10^{-2} - 1.1489 \times 10^{-2} = 5.687 \times 10^{-3}$, Then

$5.687 \times 10^{-3} = \sqrt{\frac{(6)(4.314 \times 10^{-7})}{2(1.5)}} (1.25 - 1.0)$ Or $\left(\frac{5.687 \times 10^{-3}}{0.25}\right)^2 = 8.628 \times 10^{-7} \cdot \mu_n$

$\Rightarrow \mu_n = 600 \text{ cm}^2/\text{V}\cdot\text{s}$

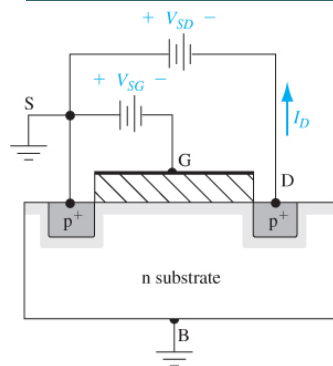
We now find

$0.132 \times 10^{-3} = \frac{(6)(600)(4.314 \times 10^{-7})}{2(1.5)} (1.0 - V_T)^2 \rightarrow \left(\frac{0.132 \times 10^{-3}}{5.1768 \times 10^{-4}}\right)^{1/2} = 1.0 - V_T$

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$V_T = 0.495\text{V}$

P-channel



$I_D = \frac{W\mu_p C_{ox}}{L} \left[(V_{SG} + V_T)V_{SD} - \frac{1}{2}V_{SD}^2 \right]$

for $0 \leq V_{SD} \leq V_{SD}(\text{sat})$

$I_D(\text{sat}) = \frac{W\mu_p C_{ox}}{2L} (V_{SG} + V_T)^2$

for $V_{SD} \geq V_{SD}(\text{sat})$

Figure 10.49 | Cross section and bias configuration for a p-channel enhancement mode MOSFET.

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Transconductances

$$g_m = \frac{\partial I_D}{\partial V_{GS}}$$

Triode region :

$$I_D = \frac{W\mu_n C_{ox}}{L} \left[(V_{GS} - V_T)V_{DS} - \frac{1}{2}V_{DS}^2 \right]$$

$$g_m = \frac{W\mu_n C_{ox}}{L} V_{DS}$$

Saturation region :

$$I_D = \frac{W\mu_n C_{ox}}{2L} (V_{GS} - V_T)^2$$

$$g_m = \frac{W\mu_n C_{ox}}{L} (V_{GS} - V_T)$$

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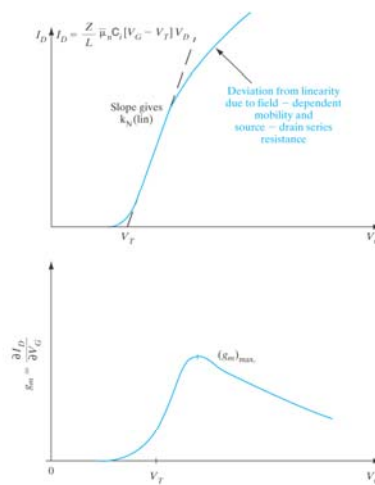
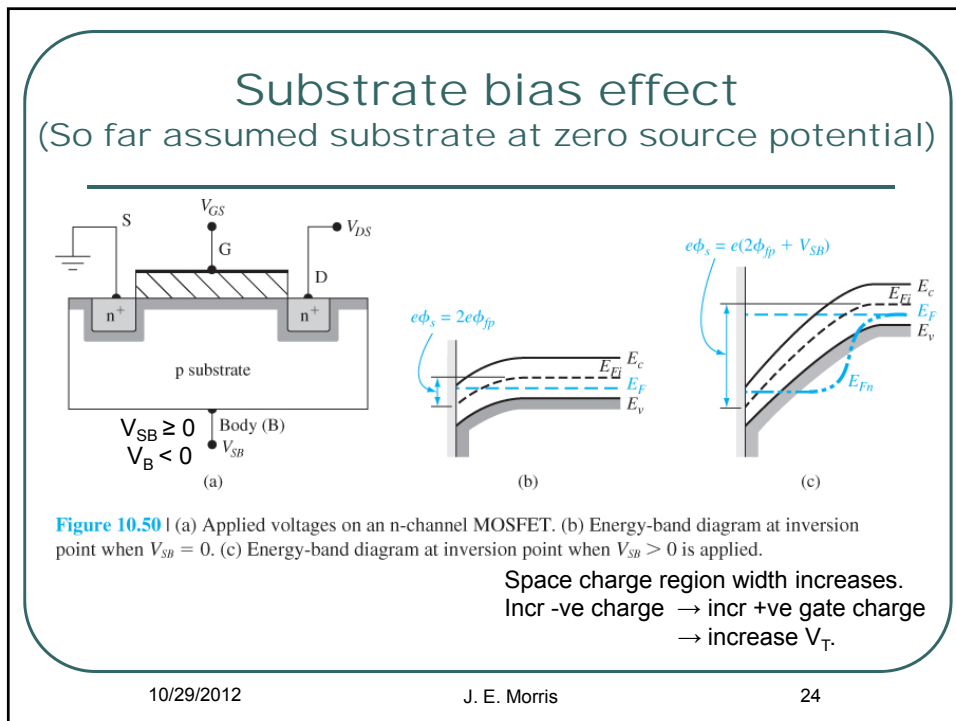
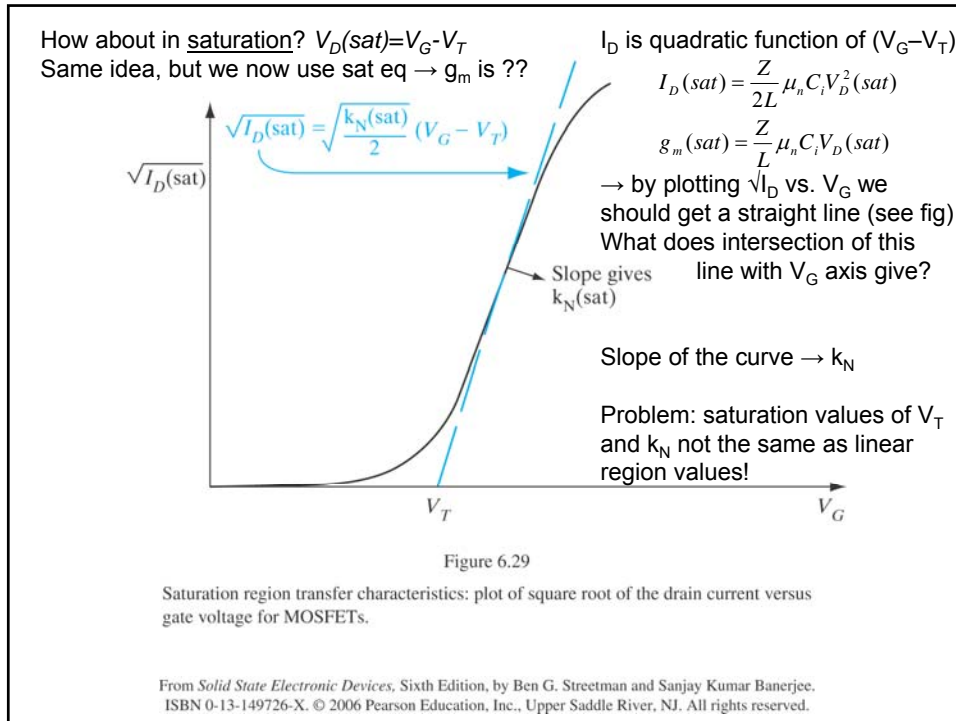


Figure 6.28

Linear region transfer characteristics: (a) plot of drain current versus gate voltage for MOSFETs in the linear region; (b) transconductance as a function of gate bias.

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Substrate bias effect: Body effect coefficient

$$V_{SB} = 0 \Rightarrow Q'_{SD}(\text{max}) = -eN_a x_{dT} = -\sqrt{2e\epsilon_s N_a (2\phi_{fp})}$$

$$V_{SB} > 0 \Rightarrow Q'_{SD} = -eN_a x_d = -\sqrt{2e\epsilon_s N_a (2\phi_{fp} + V_{SB})}$$

$$\Delta Q'_{SD} = -\sqrt{2e\epsilon_s N_a} \left[\sqrt{2\phi_{fp} + V_{SB}} - \sqrt{2\phi_{fp}} \right]$$

$$\begin{aligned} \Delta V_T &= \frac{-\Delta Q'_{SD}}{C_{ox}} \\ &= \frac{\sqrt{2e\epsilon_s N_a}}{C_{ox}} \left[\sqrt{2\phi_{fp} + V_{SB}} - \sqrt{2\phi_{fp}} \right] \\ &= \gamma \left[\sqrt{2\phi_{fp} + V_{SB}} - \sqrt{2\phi_{fp}} \right] \end{aligned}$$

where γ is the body effect coefficient

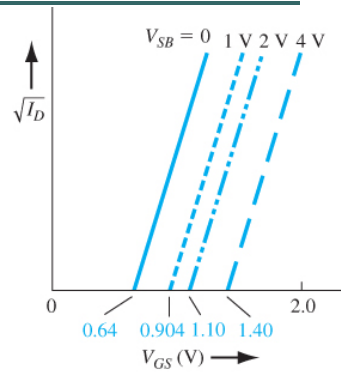


Figure 10.51 | Plots of $\sqrt{I_D}$ versus V_{GS} at several values of V_{SB} for an n-channel MOSFET.

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Ex 10.9 N-channel Si MOSFET: $N_a = 10^{16}/\text{cm}^3$, $t_{ox} = 12\text{nm}$. Find (a) body effect coefficient, & (b) the change in V_T for (a) $V_{SB} = 1\text{V}$ & (b) $V_{SB} = 2\text{V}$.

$$(a) \phi_{fp} = V_T \ln \left(\frac{N_a}{n_i} \right) = (0.0259) \ln \left(\frac{10^{16}}{1.5 \times 10^{10}} \right) = 0.3473 \text{ V}$$

$$C_{ox} = \frac{\epsilon_{ox}}{t_{ox}} = \frac{(3.9)(8.85 \times 10^{-14})}{120 \times 10^{-8}} = 2.876 \times 10^{-7} \text{ F/cm}^2$$

$$\gamma = \frac{\sqrt{2e\epsilon_s N_a}}{C_{ox}} = \frac{\sqrt{2(1.6 \times 10^{-19})(11.7)(8.85 \times 10^{-14})(10^{16})}}{2.876 \times 10^{-7}}, \quad \gamma = 0.200 \text{ V}^{1/2}$$

$$(b) \Delta V_T = \gamma \left[\sqrt{2\phi_{fp} + V_{SB}} - \sqrt{2\phi_{fp}} \right]$$

$$(i) \Delta V_T = (0.200) \left[\sqrt{2(0.3473) + 1} - \sqrt{2(0.3473)} \right] = (0.200) [1.3018 - 0.8334]$$

$$\Delta V_T = 0.0937 \text{ V}$$

$$(ii) \Delta V_T = (0.200) \left[\sqrt{2(0.3473) + 2} - \sqrt{2(0.3473)} \right] = (0.200) [1.6415 - 0.8334]$$

$$\Delta V_T = 0.162 \text{ V}$$

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High frequency effects

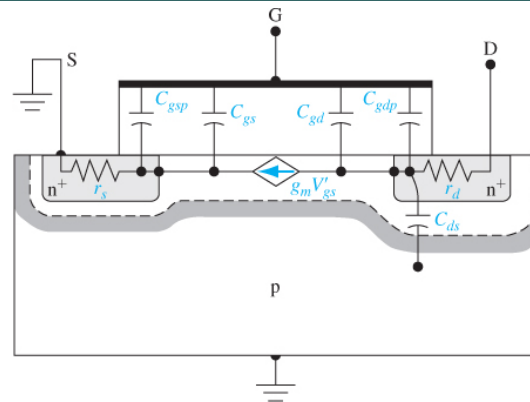


Figure 10.52 | Inherent resistances and capacitances in the n-channel MOSFET structure.

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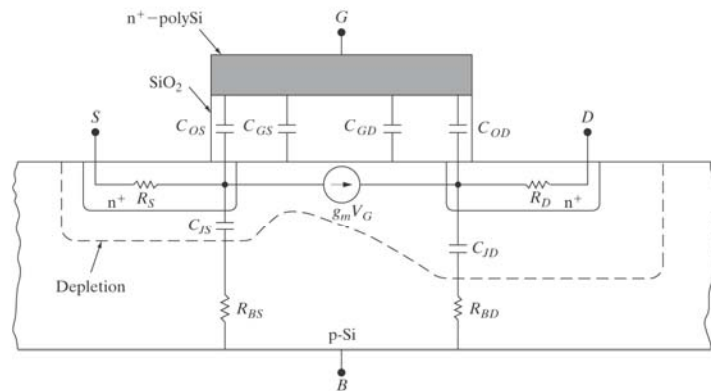


Figure 6.39

Equivalent circuit of a MOSFET, showing the passive capacitive and resistive components. The gate capacitance C_i is the sum of the distributed capacitances from the gate to the source end of the channel (C_{GS}) and the drain end (C_{GD}). In addition, we have an overlap capacitance (where the gate electrode overlaps the source/drain junctions) from the gate-to-source (C_{OS}) and gate-to-drain (C_{OD}). C_{OD} is also known as the Miller overlap capacitance. We also have p-n junction depletion capacitances associated with the source (C_{JS}) and drain (C_{JD}). The parasitic resistances include the source/drain series resistances (R_S and R_D), and the resistances in the substrate between the bulk contact and the source and drain (R_{BS} and R_{BD}). The drain current can be modeled as a (gate) voltage-controlled constant-current source.

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Small signal equivalent circuit

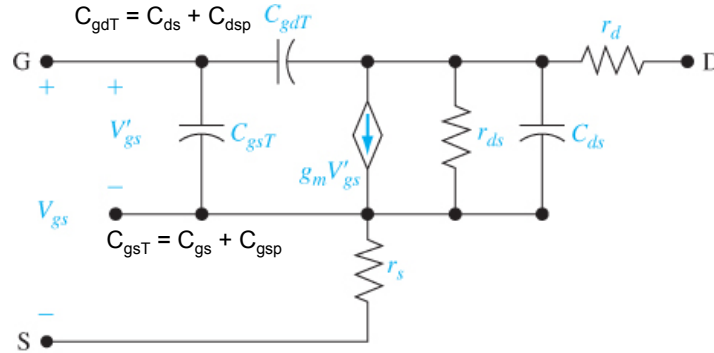


Figure 10.53 | Small-signal equivalent circuit of a common-source n-channel MOSFET.

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Simplified small-signal models

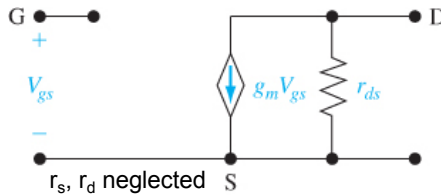


Figure 10.54 | Simplified, low-frequency small-signal equivalent circuit of a common-source n-channel MOSFET.

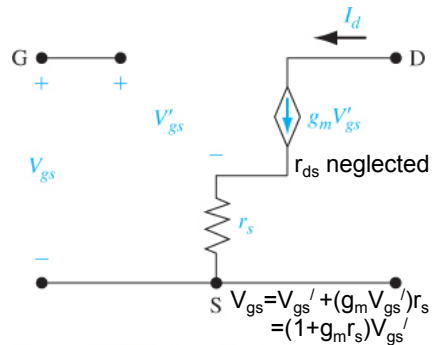


Figure 10.55 | Simplified, low-frequency small-signal equivalent circuit of common-source n-channel MOSFET including source resistance r_s .

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Cutoff frequency

Channel transit time (L/v_{sat}) not usual limitation

Input : $I_i = j\omega C_{gsT} V_{gs} + j\omega C_{gdT} (V_{gs} - V_d)$

Output : $\frac{V_d}{R_L} + g_m V_{gs} + j\omega C_{gdT} (V_d - V_{gs}) = 0$

$\Rightarrow I_i = j\omega \left[C_{gsT} + C_{gdT} \left(\frac{1 + g_m R_L}{1 + j\omega R_L C_{gdT}} \right) \right] V_{gs}$

$\approx j\omega [C_{gsT} + C_{gdT} (1 + g_m R_L)] V_{gs}$ for $\omega \ll \frac{1}{R_L C_{gdT}}$

Figure 10.56 | High-frequency small-signal equivalent circuit of common-source n-channel MOSFET.

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Cutoff frequency/Miller capacitance

$I_i \approx j\omega [C_{gsT} + C_{gdT} (1 + g_m R_L)] V_{gs}$

$= j\omega [C_{gsT} + C_M] V_{gs}$ where $C_M = (1 + g_m R_L) C_{gdT}$

$I_d = g_m V_{gs}$

$I_i = j\omega [C_{gsT} + C_M] V_{gs}$

$\left| \frac{I_d}{I_i} \right| = \frac{g_m}{\omega [C_{gsT} + C_M]}$

$\Rightarrow 1$ at $\omega_T = \frac{g_m}{C_{gsT} + C_M} = \frac{g_m}{C_G}$

In saturation :

$C_{gd} \rightarrow 0$ & $C_{gs} \approx (WL)C_{ox}$

So $f_T = \frac{g_m}{2\pi C_G} \approx \frac{\frac{W\mu_n C_{ox}}{L} (V_{GS} - V_T)}{2\pi (WL)C_{ox}}$

$= \frac{\mu_n (V_{GS} - V_T)}{2\pi L^2}$

Figure 10.57 | Small-signal equivalent circuit including Miller capacitance.

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Ex 10.10 N-channel Si MOSFET: $\mu_n=420\text{cm}^2/\text{V}\cdot\text{s}$, $t_{\text{ox}}=18\text{nm}$, $L=1\mu\text{m}$, $W=24\mu\text{m}$, $V_T=0.40\text{V}$. Find the cutoff frequency if the transistor is biased in the saturation region at $V_{\text{GS}}=1.5\text{V}$.

$$f_T = \frac{\mu_n(V_{\text{GS}} - V_T)}{2\pi L^2}$$

$$= \frac{(420)(1.5 - 0.4)}{2\pi(1.2 \times 10^{-4})^2} = 5.11 \times 10^9 \text{ Hz}$$

$$\Rightarrow f_T = 5.11 \text{ GHz}$$

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CMOS structures

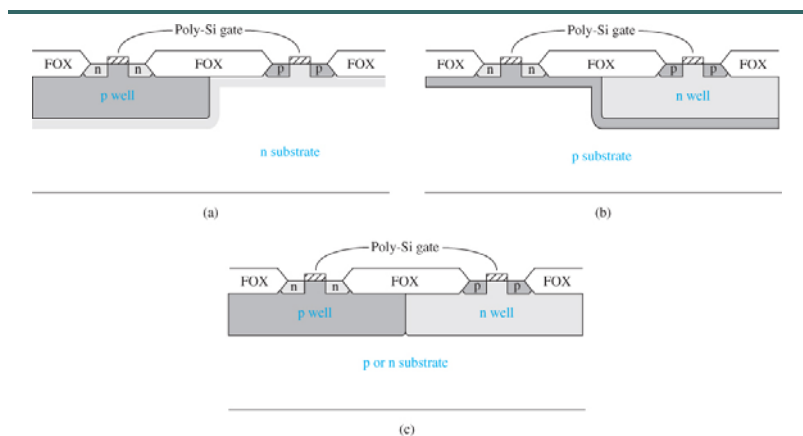


Figure 10.58 | CMOS structures: (a) p well, (b) n well, and (c) twin well.
(From Yang [22].)

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CMOS inverter

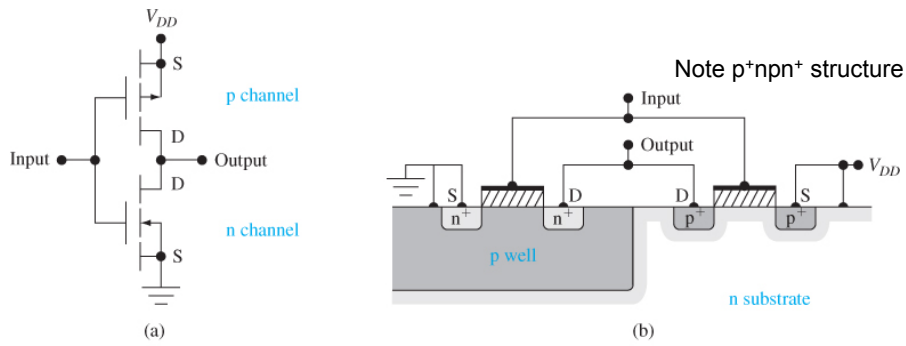


Figure 10.59 | (a) CMOS inverter circuit. (b) Simplified integrated circuit cross section of CMOS inverter.

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CMOS p⁺n⁺p⁺n⁺ structure: Latch-up

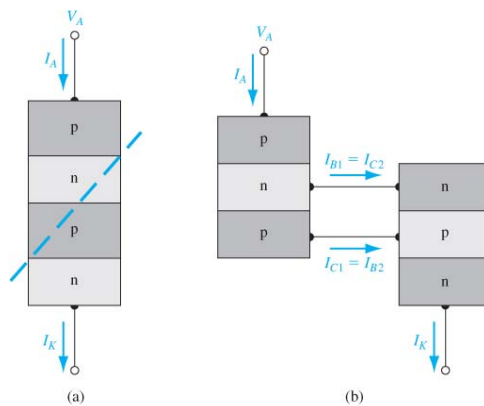


Figure 10.60 | (a) The splitting of the basic pnpn structure. (b) The two-transistor equivalent circuit of the four-layered pnpn device.

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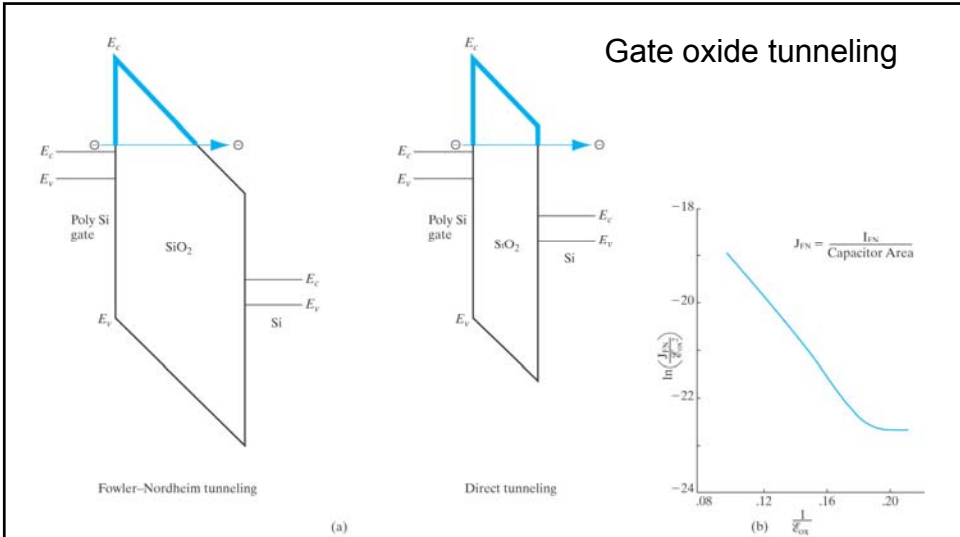


Figure 6.24

Current-voltage characteristics of gate oxides: (a) Fowler-Nordheim and direct tunneling through thin gate oxides; (b) plot of Fowler-Nordheim tunneling leakage current as a function of electric field across the oxide.

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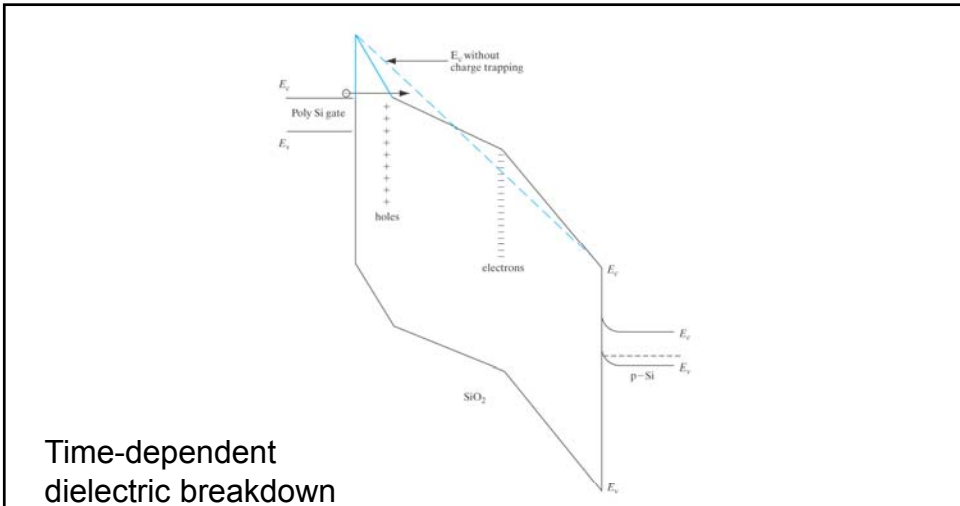


Figure 6.25

Time-dependent dielectric breakdown of oxides: Band diagram of a MOS device showing the band edges in the polysilicon gate, oxide, and Si substrate. Trapped holes and electrons in the oxide distort the band edges, and increase the electric field in the oxide near the gate. The tunneling barrier width is seen to be less than if there were no charge trapping (dashed line).

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